Course Code	Course Name	Credits
MEDO8053	Micro Electro Mechanical Systems (MEMS)	03

Objectives:

- 1. To realize the benefits and effects of scaling.
- 2. To understand properties and crystallography of Silicon
- 3. To learn the microfabrication techniques
- 4. To understand the principles and uses of micro systems

Outcomes:

After taking this course, learner should be able to:

- 1. Apply laws of scaling for development of a MEMS device
- 2. Understand the materials and their processing to make MEMS
- 3. Select and use microfabrication techniques for microsystems
- 4. Understand the development of micro sensors and actuators
- 5. Analyze microsystems technology for technical feasibility as well as practicality
- 6. Develop useful applications of MEMS.

Module	Contents	Hours
1	Introduction to MEMS	
	Unique characteristics of MEMS,	
	Microsystems Technology- An Overview, typical MEMS and	
	Microsystem Products, Scaling effects - scaling laws in	
	miniaturization- Application of MEMS	
2	Material for MEMS and manufacturing	07
	Structure of silicon and other materials - Silicon wafer processing - Bulk	
	micromachining and Surface micromachining, Wafer-bonding. Thin-film	
	deposition, Lithography, wet etching and dry etching.	
3	Micro-fabrication methods	06
	LIGA and other moulding techniques- Soft lithography and polymer	
	processing- Thick-film processing; Low temperature co-fired ceramic	
	processing.	
4	MEMS components-micro sensors	08
	Micro sensors - Basic principles and working of micro sensors- Acoustic	
	wave micro sensors- Bio-medical micro sensors- Bio-sensors- Chemical	
	microsensors – Optical Sensors – Pressure micro sensors- Thermal micro	
	sensors-acceleration micro sensors;	
5	Micro-actuators	06
	Basic principles and working of micro actuators- Electrostatic micro	
	actuators- Piezoelectric micro actuators- Thermal micro actuators- SMA	
	micro actuators- Electromagnetic micro actuators, micro valves, micro	
	pumps.	
6	Case studies /research based on MEMS applications-impact of materials,	04
	processes and design, Actuation using Shape Memory Alloys, Medical	
	device, micropumps	

Text books:

- 1. MEMS and Microsystems Design and Manufacture by Tai-Ran Hsu, Tata McGraw-Hill Publishing Company Ltd.
- 2. Foundation of MEMS by Chang Liu, Pearson Education

References:

- 1. Fundamentals of Microfabrication and Nanotechnology, by Marc J. Madou, CRC Press, 2011, ISBN: 9780849331800
- 2. Micromachined Transducers Sourcebook, by Gregory Kovacs, WCB McGraw-Hill, Boston, 1998, ISBN: 9780071164627
- 3. Micromechanical Transducers: Pressure sensors, accelerometers, and gyroscopes, by M.H. Bao, Elsevier, New York, 2000, ISBN: 978-0444505583
- 4. Microsystem Design, by Stephen D Senturia, Springer Publication, 2000, ISBN: 9780792372462.
- 5. Micro sensors Principles and Applications, by Julian W. Gardner, John Wiley & Sons, Inc.1994, ISBN: 9780471941361.